CVC Sputter Deposition

Manager: Jerry Drumheller
Backup: Sam Wright

Work Phone
254-4859
254-4836

Safety
- Keep hands, tools, & other objects away from vacuum chamber when closing it.
- No buddy system restrictions imposed on normal operation

Process Restrictions
Material Restrictions
- Samples must not extend higher than 3mm above rotating platter
- Coating area is 6" wide, but larger wafers can be put in.

Parameter Restrictions
- Do not exceed 3 KW power on metal targets, or 2 KW on non metal targets.

Scheduling / Sign-up Restrictions
- People who need multiple runs, all using the same targets are encouraged to do these runs back to back.
- Maximum 48 hours reserved in advance, with the same targets, at any time per person.
- When scheduling time on the machine you must list the targets you need in the "Process" field
- Reservations requiring target changes need to be made by 8 AM the day before your reserved time.
- Be reasonable. Let other people who need the same targets onto the schedule.
- Users/Groups may use any amount of unreserved time
- Additional individual restrictions may be imposed to maximize effective use

Requirements (Do Every Time)
- You may leave the lab while the chamber is pumping down.
- Always leave the machine under Hi Vacuum.
- Flip N2 Bleed valve UP to "Normal" when Rough pumping is finished and hvac valve has opened

Prohibitions (Never Do)
- NEVER Leave the machine while the Ion Beam cleaning is on. - NEVER Leave the machine or lab while a deposition power supply is on.

Common Problems

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<tr>
<th>Problem:</th>
<th>Root Cause:</th>
<th>Solution:</th>
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| Deposition power supply won't start | CONTINUOUS lamp is not lit on MASTER CONTROL panel | 1. Push up switch under CONTINUOUS lamp  
2. Are you enabled in "Coral"? |

Other Comments or Cautions
- OK to call machine manager (at home) about malfunctions before 10:00 p.m., and after 9:00 am. (Weekends)